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INFORMATION DISCLOSURE STATEMENT BY APPLICANT

Applicant: OKUBO et al.

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Examiner: MOORE, W.

Group Art Unit: 2826

Date: January 5, 2010

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U.S. PATENT DOCUMENTS

Examiner's Initials*	Document Number	Date MM/YYYY	Name (Family Name of First Inventor)	Class	Sub Class	Filing Date (if appropriate)
/W.M./	AR 5,770,861	06-23-1998	Hirose et al.			
	BR					
	CR					
	DR					
	ER					
	FR					
	GR					
	HR					
	IR					
	JR					
	KR					
	LR					
	MR					
	NR					

FOREIGN PATENT DOCUMENTS

Document Number	Date MM/YYYY	Country	Inventor Name	English Abstract	Translation Readily Available
				Enclosed	No
OR					
PR					
QR					
RR					
SR					
TR					

OTHER (Including in this order Author, Title, Periodical Name, Date, Pertinent Pages, etc.)

/W.M./	UR	Inkon B J et al.: "Subsurface nanoindentation deformation of Cu-Al multilayers mapped in 3D by focused ion beam microscopy," Journal of Microscopy, vol. 201, pt. 2, February 2001, pp. 256-269			X
/W.M./	VR	Dunn D N et al.: "Reconstruction of three-dimensional chemistry and geometry using focused ion beam microscopy," Applied Science Letters, vol. 75, number 21, November 22, 1999, pages 3414-3416			X
/W.M./	WR	Sakamoto T. et al.: "Development of an ion and electron dual focused beam apparatus for three-dimensional microanalysis," Japanese Journal of Applied Physics, vol. 37, no. 4A, April 1998, pages 2051-2056			X
/W.M./	XR	Supplementary European Search Report for European Application Number EP 03 75 6661 dated December 17, 2009			X

Examiner /Whitney Moore/

Date Considered: 01/15/2010

*EXAMINER: Initial if citation considered, whether or not citation is in conformance with MPEP § 609. Draw line through citation if not in conformance and not considered. Include copy of this form with next communication to Applicant.